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PATENT

Docket No. 81870004L

7/1/02  
7/24/02  
RECEIVED  
2800 MAIL ROOM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Norikazu MIZUNO, et al.

Serial No.: 09/670,917

Filed: September 29, 2000

For: SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD AND  
APPARATUS FOR REMOVING  
SILICON NITRIDE FORMED IN A  
REACTION CONTAINER (AS  
AMENDED)

Group Art Unit: 2822

Examiner: GUERRERO, Maria F.



I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents Washington D.C. 20231, on  
June 20, 2002  
Date of Deposit  
Kimberly Yee 06/20/02  
Name Date  
Signature *Kimberly Yee*

PETITION FOR EXTENSION OF TIME

Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicants respectfully petition the Commissioner for a three-month extension of time extending to June 20, 2002, the period for response to the Office Action dated December 20, 2001. A check in the amount of \$920.00 for the three-month extension fee is enclosed. The responsive papers are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

By: *Brian D. Martin*

Brian D. Martin  
PTO Registration No. 47,771  
Attorneys for Applicants

Date: June 20, 2002

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